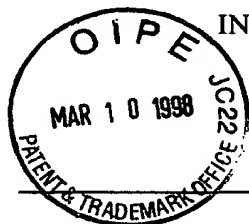


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EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
Gm	BA	5	0	6	6	3	5	7	11/19/91	Smyth Jr. et al.	219	121.69	
Gm	BB	4	9	3	0	9	0	1	06/05/90	Johnson et al.	372	26	
Gm	BC	4	6	8	4	4	3	7	08/04/87	Donelon et al.	216	66	
Gm	BD	4	4	1	4	0	5	9	11/08/83	Blum et al.	219	121.85	

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		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
													YES	NO
Gm	BE		8	-	2	1	9	6	07/22/97	Japan			English	
Gm	BF		2	2	3	3	2	6	06/05/85	East Germany				German
	BG													

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

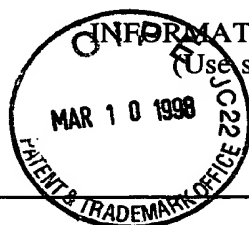
Gm	BH	Brannon, J.H., "Excimer-Laser Ablation and Etching," CIRCUITS & DEVICES magazine, September 1990 pp 19-24											
Gm	BI	Cole, H.S., Liu, Y.S., and Philipp, H.R., "Dependence of photoetching rates of polymers at 193 nm on optical absorption depth," APPL. PHYS. LETT., Vol. 48, No. 1, 6 January 1986, pp 76-77											
Gm	BJ	Dyer, P.E., and Sidhu, J., "Spectroscopic and fast photographic studies of excimer laser polymer ablation," J. APPL. PHYS. 64 (9), 1 November 1988, pp 4657-4663											
Gm	BK	4420 Laser Micromachining System - ESI Brochure (2 pages), September 1993											
Gm	BL	ESI, "Model 4570 Series Lasers Service Guide," February 1994 (REV. E 3/31/98)											
Gm	BM	Ewing, J.J., "Advanced solid-state lasers challenge conventional types," LASER FOCUS WORLD, November 1993, pp 105-110											

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AB						

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AC							
AD							

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gm	BN	Hobbs, Jerry R., "Electronics makers switch to precise micromachining tools," LASER FOCUS WORLD, March 1994, pp 69-72
gm	BO	Kulina et al., "Material bearbeitung durch Laserstrahl" <i>no date available.</i>
gm	BP	Lee, Rex A. and Moreno, W.A., "Excimer vs. ND:YAG Laser Creation of Silicon Vias for 3D Interconnects, IEEE, 1992, PP 358-360
gm	BQ	Liu, Y.S., Cole, H.S., and Guida, R., "Laser ablation of polymers for high-density interconnect," MICROELECTRONIC ENGINEERING 20 (1993) 15-29, 1993 Elsevier Science Publishers B.V., pp 15-29
gm	BR	Mahan, G.D., et al. "Theory of polymer ablation," APPL. PHYS. LETT. 53 (24), 12 December 1988, pp 2377-2379
gm	BS	Owen, Mark, "New Technology for Drilling Through - and Blind-Vias in Copper Clad Reinforced Circuit Boards, IPC Proceedings, May 1995
gm	BT	Saunders & Dolleymore, December 2, 1997 third party comments (pp 1-6 and sections 1 and 2), and EPO Form 2022
gm	BU	Saunders & Dolleymore, November 13, 1997 third party comments (pp 1-3), and EPO Form 2022

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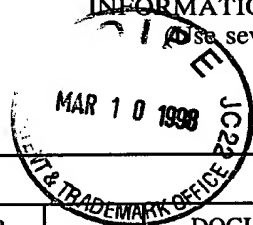
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	AC					
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	AE					

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	AF						
	AG						
	AH						
	AI						
	AJ						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

Gm	BV	Srinivasan, R., and Braren, B., "Ultraviolet Laser Ablation of Organic Polymers," CHEMICAL REVIEWS, 1989, Vol. 89, No. 6
Gm	BW	Tessier, Theodore G. and Chandler, Jerry, "Compatibility of Common MCM-D Dielectric with Scanning Laser Ablation Via Generation Processes," IEEE (1993), pp 39-45
Gm	BX	"Trepanning Moves in on Mini Holes," MACHINERY AND PRODUCTION ENGINEERING, 2 November 1983, pp 42-43
Gm	BY	Wiener-Avnear, Eli, "Lasers cut microscopic paths with major potential," LASER FOCUS WORLD, July 1993, pp 75-80
Gm	BZ	Wu et al., "Single-Shot Excimer Laser Ablation of Thick Polymers Desists on Metallic Substrates," AMP Journal of Technology, Vol. 1, November 1991, pages 69-79.

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